

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

In re application of :
Makoto AKIZUKI et al. :
Serial No. NEW : **Attn: APPLICATION BRANCH**
Filed August 27, 2003 : Attorney Docket No. 2003-1240

METHOD FOR FORMING GAS CLUSTER
AND METHOD FOR FORMING THIN FILM
**(Rule 1.53(b) Continuation
of Serial No. 10/025,899,
Filed December 26, 2001)**

PRELIMINARY AMENDMENT

Commissioner for Patents
P.O. Box 1450
Alexandria, VA 22313-1450

Sir:

In the interest of compact prosecution, please amend the present application as follows: